Abstract

The present invention relates to a plasma generating device comprising a plasma source having a plasma source hollow body (1) and an electron emission unit (5) which makes it possible to emit free electrons into the plasma source hollow body, wherein the plasma source hollow body (1) has a first gas inlet (7a) and a plasma source opening (10) which forms an opening to a vacuum chamber, and further comprising an anode having an anode hollow body (2), wherein the anode hollow body (2) has a second gas inlet (7b) and an anode opening (11) which forms an opening to the vacuum chamber, and a voltage source (8) the negative pole of which is connected to the electron emission unit (5) and the positive pole of which is connected to the anode hollow body (2), wherein the positive pole of the voltage source (8) is additionally electrically connected by means of a first shunt (6a) to the plasma source hollow body.

(Figure 1)